

Image



Atty. Dkt. No. 025311-0114

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Satoshi KUME
Title: APPARATUS AND METHOD OF
CLEANING A SUBSTRATE
Appl. No.: 10/050,161
Filing Date: 01/18/2002
Examiner: Michail Kornakov
Art Unit: 1746

RESPONSE TO RESTRICTION REQUIREMENT

Mail Stop NON-FEE AMENDMENT
Commissioner for Patents
PO Box 1450
Alexandria, Virginia 22313-1450

Sir:

In response to the restriction requirement set forth in the Office Action mailed February 17, 2004, Applicant hereby provisionally elects Group I, Claims 1-7 drawn to a substrate cleaning apparatus, for examination.

Applicants, of course, reserve the right to file one or more divisional applications covering the subject matter of the non-elected claims.

Applicants respectfully request examination on the merits of this application. If the Examiner believes, for any reason, that personal communication will expedite prosecution of this application, the Examiner is invited to telephone the undersigned at the number provided.

Respectfully submitted,

Date 3/8/04

By WT Ellis

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